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SJB  
FEB 11 2003

PATENT  
P114-US

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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail on January 30, 2003 in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

Patti Crowder  
Patti Crowder

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In the application of: Mathieu et al.  
Application No.: 09/527,931  
Filing Date: March 17, 2000  
For: Method And Apparatus For Burning-In  
Semiconductor Devices In Wafer Form

Examiner: R. Chang  
Group Art Unit: 3919

**NOTICE OF RELATED PATENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Applicants wish to draw the Examiner's attention to the following commonly owned patent (and the art cited therein), whose subject matter may be deemed related to the subject matter of the above-identified application.

US pat. no.: 6,509,751 (P101-US) issued January 21, 2003

Respectfully submitted,

Date: January 30, 2003  
By: N. Kenneth Burraston  
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